CLAIMS

1. A vacuum process apparatus for processing at least one workpiece, comprising:

- at least two stations for treating or handling said workpiece and having each at least one opening for the workpiece;
- a transport device rotatable around an axis;
- a drive arrangement for rotating said transport device;
- at least two conveyor means arranged at said transport device for at least one workpiece each;
- driving means at said transport device respectively, coupled to said conveyor means to individually move said conveyor means relative to said transport device.
- 2. The apparatus of claim 1, said openings defining an opening area each, the normals on said areas being warped with respect to said rotational axis.
- 3. The apparatus of claim 1, said conveyor means being movable at least one of parallel to said rotational axis and of radially with respect to said rotatational axis.
- 4. The apparatus of claim 1, said conveyor means, once positioned adjacent one of said openings by rota-

tion of said transport device, being movable towards and from said opening in a direction given by the normal on the opening area defined by said opening.

5. The apparatus of claim 1, rotation of said transport device around said rotational axis substantially defined a cone shaped trajectory surface with a cone opening angle with respect to said rotational axis of not more than 90°.

The apparatus of claim 5, said openings defining an opening area each, the normals on said areas pointing in direction of respective generatrix of said trajectory cone surface.

- 7. The apparatus of claim 6, said openings being arranged along a circle cut by said trajectory cone surface by a geometric plane arranged perpendicularly to said rotational axis.
  - 8. The apparatus of claim 1, said transport device comprising a transport arm for each of said conveyor means, said arms projecting from said rotational axis.
  - 9. The apparatus of claim 8, said arms comprising said driving means.

10. The apparatus of claim 1, said station communicating by said opening with a chamber, said transport device residing within said chamber.

11. The apparatus of claim 10, further comprising gas

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inlet means and pumping means at least at one of said chambers, stations and of said chamber.

12. The apparatus of claim 1, at least one of said conveyor means comprising a seal member for sealingly closing the opening of at least one of said stations.

13. The apparatus of claim 10, said chamber being vacuum tight.

The apparatus of claim, said seal member being formed by a conveyor plate for said workpiece.

comprising a conveyor plate with a projecting positioning pin for positioning a disk shaped workpiece with central bore.

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16. The apparatus of claim 15. further comprising holding means for said workpiece on said conveyor plate.

The apparatus of claim 16, said holding means being formed by spring means acting radially with respect to said pin.

The apparatus of claim 1, said workpieces being one of compact disk workpieces and of magneto-optical storage disk workpieces.

19. A holding arrangement for disk shaped workpieces with a central bore during vacuum treatment, comprising a support plate with an upstanding pin for said

bore; spring loaded holding portions around said pin being biased radially outwardly with respect to said pin, and further comprising holding portions projecting outwardly with respect to said pin and being biased slightly outside the surface of said pin.

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